

Theory and Technology of Semiconductor Devices
Assignment 2

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Due: Dec 22

Problem 1 Doing an Arsenic diffusion on a p-type wafer with background doping of 10^{17}cm^{-3} with limited amount of Arsenic (constant-total-dopant) of 10^{14}cm^{-2} at 1100°C for 1.5 hr, find the surface concentration and junction depth.
Note: $D = 2.07 \times 10^{-14} \text{cm}^2/\text{s}$ for Arsenic at 1100°C